

Special Issue

Advances in Optical MEMS and Laser Technologies

Message from the Guest Editor

Modern Si-Technology delivers compact, highly integrated and energy-efficient solutions for research and industrial applications. Optical components, in the other hand, is one of the central research activities nowadays, driven by strong developments in areas such as consumer, automotive, as well as precise metrology, high secure communication and quantum technology. Si based, miniaturized optical systems combines the above mentioned strengths of high integration level, energy efficiency, compactness and high precision. Continues material development and manufactory progress for Si-technology and optical components even make this topic fusion growingly interesting and highly performant. In this Special Issue, we'd like to encourage authors to present their current result on designs, modelling, analysis, characterization, fabrication and applications for optical MEMS. The potential topics include, but are not limited to MEMS optical systems, integrated light source, wave guide, laser projection, LIDAR sensor system or quantum technology etc.

Guest Editor

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